

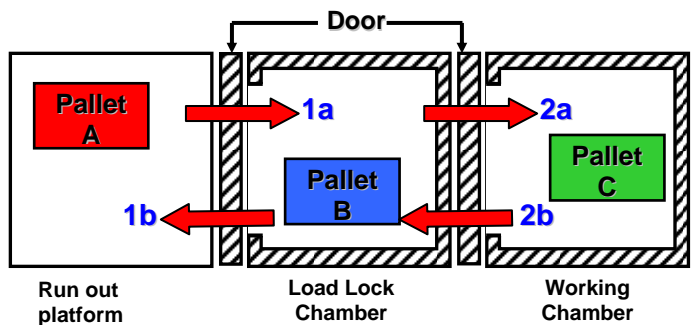
Electron Beam Machines

S 20-6

- 150 kV U_B (max.)
- 30 kW beam beam power (max.)
- load lock machine (2m^3 working chamber)
- CCD window
- ELO monitoring
- dynamic lens
- CNC control (Sinumerik 840D, SPS)
- complete coverage of the machine parameters
- working chamber & leaded load lock chamber can jointly serve as chamber system
- maximum component length >1600mm

Equipment Upgrade:

- extra-length single spindle
- tiltable turntable, turn tilting device
- horizontal beam generator height-adjustable
- wire feed for 0.6-1.8 mm dia. wire



K 25

- 80 kV U_B (max.)
- 40 kW beam beam power (max.)
- CCD window
- ELO monitoring
- dynamic lens
- dual lens
- CNC control (Sinumerik 840D, SPS)
- complete coverage of machine parameters
- chamber machine (2.5m^3)
- horizontally or vertically flanged beam generator
- turning device

